

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Takeshi Nakamura et al. Art Unit : Unknown
Serial No. : Examiner : Unknown
Filed : Herewith
Title : MULTILAYER SUBSTRATE MANUFACTURING METHOD

Commissioner for Patents
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Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

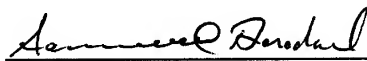
Applicants request consideration of the references listed on the attached PTO-1449 form.
English language translations are also enclosed.

The relevance of Desig. ID nos. AL-AO is indicated in the enclosed International Search Report.

This statement is being filed with the application. Please apply any charges or credits to Deposit Account No. 06-1050.

Respectfully submitted,

Date: 8/31/06



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Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 14225-112US1	Application No.
Information Disclosure Statement by Applicant (Use several sheets if necessary)		Applicant Takeshi Nakamura et al.	
		Filing Date	Group Art Unit
(37 CFR §1.98(b))			

U.S. Patent Documents							
Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

Foreign Patent Documents or Published Foreign Patent Applications								
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
	AL	2003-318535	11/07/2003	Japan			X	
	AM	2002-290044	10/04/2002	Japan			X	
	AN	08-153976	06/11/1996	Japan			X	
	AO	2002-329964	11/15/2002	Japan			X	
	AP	2003-324263	11/14/2003	Japan			X	

Other Documents (Include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
	AQ	
	AR	
	AS	
	AT	

Examiner Signature	Date Considered
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	